



PATENT

Atty. Dkt. AMAT/5434.Y2/DISPLAY/AKT/RKK

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Shang, et al.

Serial No.: 09/741,529

Confirmation No.: 6382

Filed: December 19, 2000

For: On-Site Cleaning Gas Generation
For Process Chamber Cleaning

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Group Art Unit: 1746

Examiner: Michael Kornakov

MAIL STOP RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE UNDER 37 CFR 1.10

I hereby certify that this correspondence is being deposited on December 19, 2003 with the United States Postal Service in an envelope as "Express Mail Post Office to Addressee," mailing label No. EV335470745US addressed to: Mail Stop RCE, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

12/19/03

Date

Keith M. Tackett

Signature

RESPONSE TO SUBMISSION BY STEVEN R. SPRINKLE

Applicant has reviewed the "References for Consideration by Examiner" submitted by Steven R. Sprinkle and note that Mr. Sprinkle does not show that any of the references relate to the claims allowed by the Examiner. The allowed claims include a cold trap which separates HF from F₂ prior to using the F₂ to clean a chamber. Mr. Sprinkle asserts that the references teach or suggest cleaning a chamber with a mixture of HF and F₂ as claimed by Applicant. However, the allowed claims do not require cleaning a chamber with a mixture of HF and F₂ as erroneously asserted by Mr. Sprinkle. Moreover, Mr. Sprinkle fails to identify any teaching or suggestion of a cold trap to remove HF as recited in the allowed claims.

Respectfully submitted,

Keith M. Tackett

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